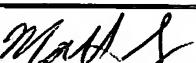


Form PTO-1449			ATTY. DOCKET NO. 1691-0177PUS2		APPLICATION NO. NEW		
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)			APPLICANT Hiroyuki FUKUYAMA et al.				
			FILING DATE March 26, 2004		GROUP		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	KIND	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
M	US 5,741,724	A	1998-04-21	Ramdani et al.			
	US						
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FOREIGN PATENT DOCUMENTS							
Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION
							YES
M	JP 2-141495	A	1990-05-30	JAPAN			Abs
M	JP 2-153897	A	1990-06-13	JAPAN			Abs
OTHER DOCUMENTS (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)							
M	T. SHIBATA et al., "Characterization of high-quality epitaxial AlN films grown by MOVPE", Mat. Res. Soc. Symp. Proc., Vol. 693, 2002, pp. I9.3.1-I9.3.4, Material Research Society.						
EXAMINER				DATE CONSIDERED			
						4/19/2005	
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